

## IN THE SPECIFICATION

Please amend the specification as follows:

On Page 1, first paragraph:

--The present invention relates to a mass flow controller. More particularly it relates to a compact mass flow controller module free from the consequences of variation in pressure effects.--

On Page 1, fourth paragraph:

--The pressure of the gases  $G_1$ ,  $G_2$  supplied from the cylinders 14, 15 is usually reduced to about 98 kPa at the outlet side, and by further reducing to about 30 kPa, for example, by the pressure regulators 16a to 16d, the gases are supplied into the mass flow controllers 18a to 18d, so that damage of mass flow controllers 18a to 18d may be prevented. The manager of semiconductor manufacturing line controls the mass flow controllers 18a to 18d so as to supply gases  $G_1$ ,  $G_2$  at specified flow [[rat e]] rate in the chambers 11, 12, and adjusts the pressure regulators 16a to 16d while observing the gauges 17a to 17d, and therefore adjusts properly the pressure of gases  $G_1$ ,  $G_2$  to be supplied into the mass flow controllers 18a to 18d.--

On Page 3, second paragraph:

-- The present invention [[is]] has been devised in the light of the above problems, and it is hence an object thereof to present a mass flow controller capable of controlling always stably at setting flow rate in spite of pressure fluctuations at either upstream side or downstream side of the mass flow controller.--

On Page 3, please insert the following between Paragraph 2 and Paragraph 3:

--It is an object of the present invention to provide a mass flow controller module capable of being installed as a unitary component for stably controlling a set flow rate in spite of possible pressure fluctuations at either an upstream side or a downstream side of the mass flow controller.--

On Page 5, fifth full paragraph:

--The pressure control valve 4, flow rate sensor 5, and flow rate control valve 6 are aligned at one side (upper side) of the passage block 3 with pre-formed fluid connections such as valve seats 3c, 3d and flow rate sensor ports, and hence the overall size of the mass flow controller is suppressed reduced and made compact--

On Page 7, third full paragraph:

-- In the mass flow controller 1 of the invention, the control unit 8b controls the pressure control valve 4 by feedback to a specified pressure  $P_c$  by using the pressure signal  $S_{pb}$  from the pressure sensor 7b, and therefore if the inlet side pressure  $P_1$  of the mass flow controller 1 fluctuates due to some effects, the mass flow controller 1 can be controlled control stably. Besides, since the control unit 8a controls the flow rate control valve 6 by feedback so that the measured flow rate  $F$  may conform to the preset flow rate  $F_s$  by using the flow rate signal  $S_f$  from the flow rate sensor 5, and therefore if the outlet side pressure  $P_2$  of the mass flow controller 1 fluctuates, it is free from its effects---

On Page 8, second full paragraph:

--Also, in the this embodiment, the pressure control valve 4 and flow rate sensor 5 are arranged side by side, and the second passage 2b disposed between them is designed to be as

short as possible in length, and hence the any time delay of pressure  $P_c$  with respect to the output of the opening degree control signal  $C_p$  of the pressure control valve 4 is minimized, and fluctuations of pressure  $P_c$  in the section of the flow rate sensor 5 are made as small as possible.-

On Page 8, fourth full paragraph:

--In addition, by eliminating the fitting and piping from the second passage 2b between the pressure control valve 4 and flow rate sensor 5, it [[is]] becomes free from the risk of a pressure drop due to any passage resistance or gas leak.--

On Page 9, third full paragraph:

--That is, by using the mass flow controller 1 of the present invention, if sudden pressure fluctuations occur whether at the upstream side pressure  $P_1$  or at downstream side pressure  $P_2$ , a specified flow rate continues [[t o]] to flow always [[by]] under a very stable control.--

On Page 9, fifth full paragraph:

-- In Fig. 3, reference numerals 1a to 1d are the mass flow controller 1 of the invention. That is, by using the mass flow controller 1 of the invention, the gas feed lines 13a to 13d can be composed in a very simple structure, and the time and labor for building the gas feed lines 13a to 13d can be saved. At the same time, only a small area is required for installing the gas feed lines 13a to 13d.--